

ABSTRACT

SUBSTRATE HEAT TREATMENT APPARATUS,
SUBSTRATE HEAT TREATMENT METHOD,
5 STORAGE MEDIUM AND
HEAT-TREATMENT-CONDITION DETECTING APPARATUS

A substrate heat treatment apparatus includes: a placement
unit on which a substrate is placed; a heat treatment unit for
10 heating or cooling the substrate on the placement unit; a
plurality of temperature sensors positioned correspondingly to a
plurality of locations of the substrate on the placement unit; and
a control unit. The control unit is configured to control the heat
treatment unit based on temperatures detected by the
15 temperature sensors, to calculate a position of a thermal center
of gravity of the substrate based on the temperatures detected
by the temperature sensors, and to detect heat treatment
condition of the substrate based on the position of the thermal
center of gravity.

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Fig. 4